

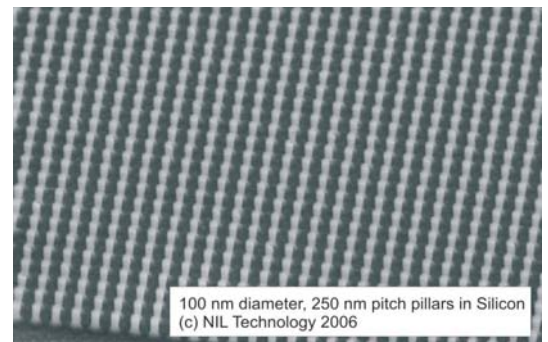
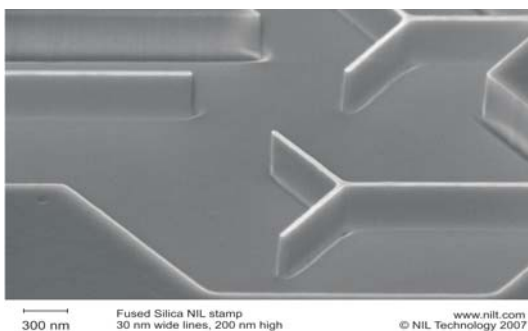
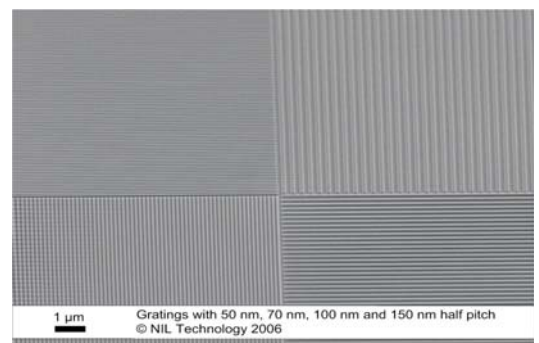
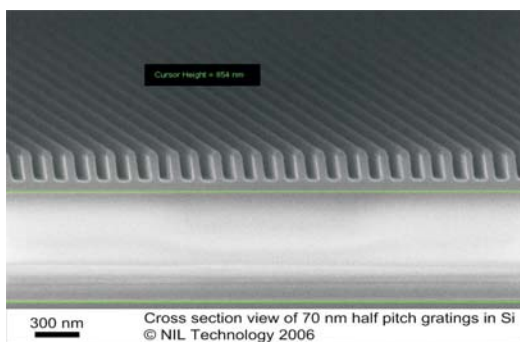
NILT[®] Custom Stamps



Customized Stamps for Nanoimprint Lithography

Features:

- Engineered to order
- Sub 20 nm resolution
- Pitch from 40 nm
- Both thermal NIL and UV NIL
- Fabrication of stamps to all NIL tools



General specifications:

Stamp materials:	Silicon, Fused Silica and Nickel
Stamp size:	Up to 6-inch
Pattern size:	Below 20 nm
Pattern pitch:	From 40 nm
Aspect ratio:	Better than 2:1 for high resolution
Pattern type:	Positive and negative profile stamps
Defect area:	<1%